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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Toshiya SATOH et al.
Serial No.: 09/809,181
Filed: March 16, 2001
For: **SEMICONDUCTOR DEVICE AND MANUFACTURING
METHOD FOR HIGH RELIABILITY AND PRODUCTION YIELD
RATE WITH MINIMAL DAMAGE DUE TO APPLICATION OF
MECHANICAL STRESS AND THERMAL STRESS**
Group: 2815
Examiner: Jose R. Diaz

RESPONSE TO OUTSTANDING OFFICE ACTION

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

August 19, 2004

Sir:

In response to the Office Action (Paper No. 20040315) dated on March 25, 2004, please amend the above-identified application as follows.

Listing of the Claims begin on page 2 of this paper.

Remarks/Arguments begin on page 9 of this paper.